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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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Shannon L. Stewar

Appl No.

: 10/593,857

Confirmation No. 5813

Applicant

: Kim, Nam Hun

Filed

: September 22, 2006

Title

: PLASMA CHAMBER HAVING PLASMA SOURCE COIL AND

METHOD FOR ETCHING THE WAFER USING THE SAME

TC/A.U.

: 1792

Examiner -

: Duy Vu Nguyen Deo

Docket No.

: 58409/N305

Customer No.

: 23363

AMENDMENT

Mail Stop Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Post Office Box 7068 Pasadena, CA 91109-7068 October 23, 2008

Commissioner:

In response to the Office action of June 23, 2008, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 4 of this paper.